

TECHNICAL SPEC FOR Ion Implanter

System Model:

Axcelis 6200AV

- **Wafer size? 6 inch**
- **Wheel type? none**
- **Wafer tilt? 0/45**
- **Source (i.e. Bernas or IHC)? bernas**
- **Extraction system (i.e. dual bellows)? fixed**
- **Gases? Boron, phosfine**
- **SDS Gas box? sds**
- **Max implantation energy (in KeV)? 180**
- **Max Extraction voltage (in KeV)? 20**
- **Heat Exchanger? no**

- **Orienter type (flat, notched, etc...)?**
- **Hydrogen implantation available?**
- **Number of trays?**
- **Load and unload locks:**
- **Source extraction alignment jig**
- **AMU**
- **Beamline column**
- **Mechanical clamp:**
- **Turbo type?**
- **PC type:**
- **Cryo type?**
- **PFS standard or HD?**